

#### Fabrication of pre-structured substrates and Cu-In-Ga precursor deposition for Cu(In,Ga)Se<sub>2</sub>-based micro-concentrator solar cells

#### NANOTECHNOLOGIES

Marina Alves <sup>1,2</sup>, Joaquim Carneiro <sup>2</sup>, Sascha Sadewasser <sup>1</sup>

<sup>1</sup>International Iberian Nanotechnology Laboratory (INL), Av. Mestre José Veiga s/n, 4715-330 Braga, Portugal; <sup>2</sup>Centre of Physics of Minho and Porto (CF-UM-UP), Gualtar Campus, 4800-058 Guimarães, Portugal

# Introduction

- Cu(In,Ga)Se<sub>2</sub> (CIGS) concentrator solar cells have reached a record efficiency of 23.3%<sup>1</sup>.
- > The micro-concentrator concept combines thin-film photovoltaic technology with concentrator photovoltaic (CPV) technology, downscaling the solar cell to the micrometer range<sup>2</sup>.
- > The miniaturization of the CIGS absorber layer allows to reduce the use of critical raw materials In and Ga and enhances the efficiency<sup>3</sup>.
- > In this work, we demonstrate the fabrication process for pre-structured substrates with arrays of holes with 200 to 250  $\mu$ m diameter inside a SiO<sub>x</sub> insulating matrix. Followed by Cu-In-Ga (CIG) precursor deposition, thermal annealing of the precursor, and selenization to create CIGS absorber micro-dots.

# **Pre-structured substrate** microfabrication

- a) Mo deposition by sputtering
- b) SiO<sub>v</sub> deposition by PECVD
- Photoresist coating C)
- d) Exposure by Direct Write Laser
- Photoresist e) development
- Reactive ion etching of f)

SiO~

- a) CIG deposition by sputtering
- Photoresist removal h) Selenization by CVD i)

Some processes needed to be adapted the to substrate used

#### Cu-In-Ga precursor deposition

- 1 µm CIG deposition by sputtering.
- As-deposited CIG precursor with In-rich islands with height ~600 nm.
- > Thermal annealing was performed to remove resist incorporated during sputtering, improve CIG quality and assess substrate stability.
- ➤ Thermal annealing at 500 °C leads to less. defined islands.
- SiO<sub>x</sub> matrix stable during thermal annealing.

# **Selenization**

1-stage selenization and/or rapid heating/cooling of the CVD system resulted in blisters, cracks and/or delamination.



- Less CIGS damage during selenization by heating up with a ramp of 10 °C/min and a 2-stage selenization at 100/480 °C.
- $\succ$  $1 \,\mu m \, SiO_x$  matrix presented significant damage after selenization.

### Conclusions

- Thermal annealing is crucial to improve CIG precursor before selenization.
- > Selenization parameters strongly influence the CIGS absorber layer, such as heating/cooling ramp, temperature and amount of Se.
- Further optimization of the selenization process required to improve the CIGS micro-dots.

## Acknowledgements

Marina Alves thanks the Fundação para a Ciência e a Tecnologia (FCT), República Portuguesa and União Europeia/FSE for the PhD grant 2020.06063.BD.





REPÚBLICA PORTUGUESA

CIÊNCIA, TECNOLOGIA E ENSINO SUPERIOR

#### References

<sup>1</sup>M. A. Green et al., Prog. Photovoltaics Res. Appl. 31, 3 (2023). <sup>2</sup> M. Paire et al., Energy Environ. Sci. 4, 4972 (2011). <sup>3</sup> M. Alves et al., J. Phys. Energy 2,. 012001 (2020).







